

Form PTO-1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark OfficeAttorney Docket No.
740756-2419Serial No. Not Yet
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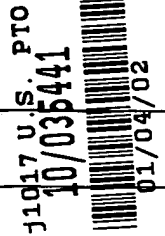
INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Applicant: Naoaki YAMAGUCHI et al.

Filing Date: January 4, 2002

Group: 1746



U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
ACA	5,808,318	09/15/1998	Masumo et al.			
	5,904,550	05/18/1999	Yamaguchi			
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✓	4,469,551	09/04/1984	Laude			

Examiner Anita Hlanbo

Date Considered 2/10/03

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Form PTO-1449 (Rev. 8-83)		U.S. Department of Commerce Patent and Trademark Office		Attorney Docket No. 740756-2419		Serial No. Not Yet Assigned	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)							
				Applicant: Naoaki YAMAGUCHI et al.			
				Filing Date: January 4, 2002		Group: 1746	
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation Yes No	
✓	05-243576	09/21/1993	Japan			Abstract	
↓	08-051078	02/20/1996	Japan			Abstract	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
✓		F. Ueno, "Observation of fast microscopic phase change phenomena of chalcogenide thin films", Japanese Journal of Applied Physics, Supplement, Vol. 26, Supplement 26-4, pp. 55-60, 1987.					
		N. Kondo et al., "Film thickness measurement of ultrathin film using light of UV wavelength" Proceedings of the SPIE, Vol. 1673, pp. 392-402, 1992.					
		C. Hayzelden et al., "In Situ Transmission Electron Microscopy Studies of Silicide-Mediated Crystallization of Amorphous Silicon" (3 pages) Appl. Phys. Lett. 60(2) pp. 225-227, 1/1992.					
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		R. Kakkad, J. Smith, W.S. Lau, S.J. Fonash, "Crystallized Si Films By Low-Temperature Rapid Thermal Annealing of Amorphous Silicon", J. Appl. Phys. 65 (5), March 1, 1989, 1989 American Institute of Physics, pp. 2069-2072.					
		G. Liu, S.J. Fonash, "Polycrystalline Silicon Thin Film Transistors on Corning 7059 Glass Substrates Using Short Time, Low Temperature Processing", Appl. Phys. Lett 62 (20), May 17, 1993, 1993 American Institute of Physics, pp. 2554-2556.					
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✓		R. Kakkad, G. Liu, S.J. Fonash, "Low Temperature Selective Crystallization of Amorphous Silicon", Journal of Non-Crystalline Solids, Volume 115, (1989), pp. 66-68.					
Examiner <i>Anita Alenka</i>				Date Considered 2/10/03			
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				Application Number	10/035,441
				Filing Date	January 4, 2002
				First Named Inventor	Naoaki YAMAGUCHI et al.
				Group Art Unit	1746
				Examiner Name	Unassigned
Sheet	1	of	1	Attorney Docket Number	0756-2419

U.S. PATENT DOCUMENTS						
Examiner Initials ¹	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
WJL		5,472,505		Lee et al.	12/05/95	

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		Office ³	Number ⁴	Kind Code ⁵ (if known)				
WJL		JP	6-204132		Nakatani et al.	07/22/94		Abst.

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

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